

<b>Notice of References Cited</b>	Application/Control No. 10/653,035	Applicant(s)/Patent Under Reexamination CHAMBERS, SCOTT A.	
	Examiner Matthew J Song	Art Unit 1765	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	C	US-5,362,711	11-1994	Takada et al.	505/476
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	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Lu et al. "Improved method of nonintrusive deposition rate monitoring by atomic absorption spectroscopy for physical vapor deposition processes". J. Vac. Sci. Technol. A 13(3), May/June 1995. pp 1797-1801.
	V	Hu et al. "Structural tuning of the magnetic behavior in spinel-structure ferrite thin films" Physical Review B Vol. 62, num. 2, Jul 2000, pp R779-R782.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.